

Docket No. 212/543

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

In re Application of:

Darymple, et al.

Serial No.: 10/754,360

Filed: January 8, 2003

For: Devices and Methods for
Optical Endpoint Detection
During Semiconductor Wafer
Polishing

Art Unit: 1763

Examiner: MacArthur, Sylvia

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TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT


Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313

Sir:

Enclosed please find Applicants' Information Disclosure Statement. Each item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this information disclosure statement.

Date: July 11, 2003

By:


Marc J. Frechette, Esq.
Reg. No. 49,060

FORM PTO-1449 (REV. 7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 212/543		SERIAL NO. 10/754,360	
LIST OF PRIOR ART CITED BY APPLICANT (use several sheets if necessary)				APPLICANT Darymple, et al.			
				FILING DATE January 8, 2003		GROUP 1763	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA	2003/0109196	6/03	Wolf	451	6	
	AB	2005/0101224	5/05	Johansson	451	8	
	AC	6,230,069	5/01	Campbell	700	121	
	AD	5,665,199	9/97	Sahota	438	14	
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
FOREIGN PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	AL						
	AM						
OTHER PRIOR ART (including Author, Title, Date, Pertinent Pages, Etc.)							
EXAMINER				DATE CONSIDERED			
Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant							